

Applicant(s): Isamu Kobori et al.
METHOD OF MANUFACTURING A SEMICONDUCTOR
METHOD OF MANUFACTURING A THIN-FILM TRANSISTOR
AND THIN-FILM TRANSISTOR

Fig. 1

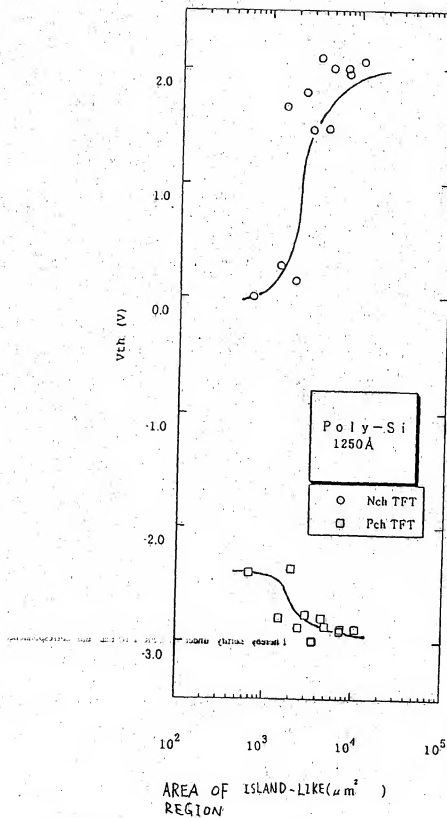
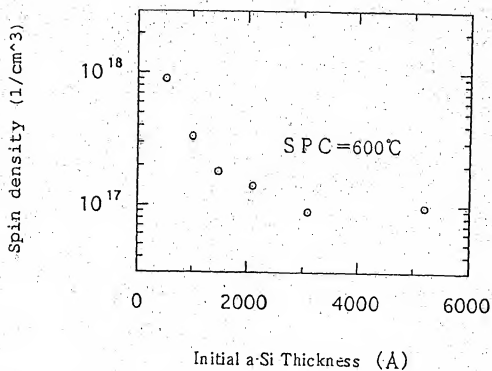


Fig. 2



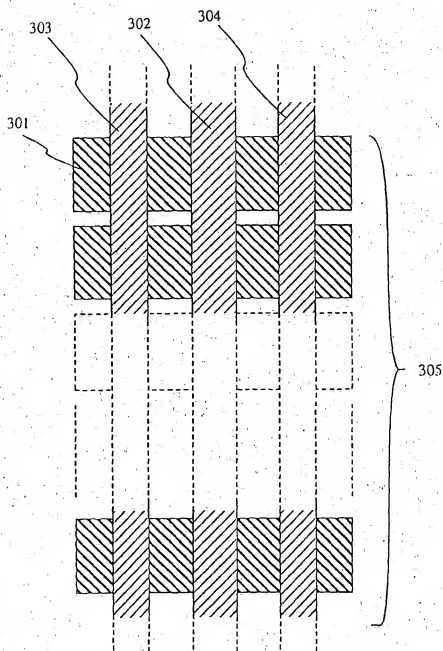
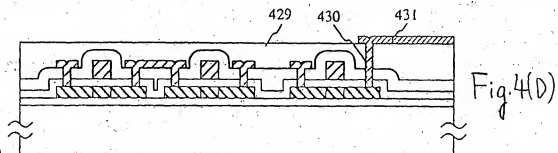
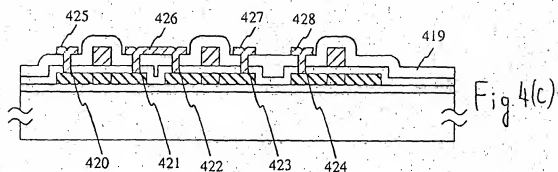
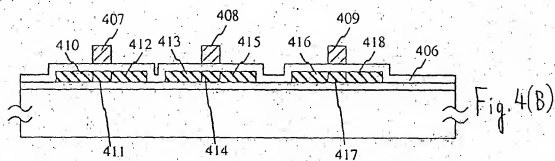
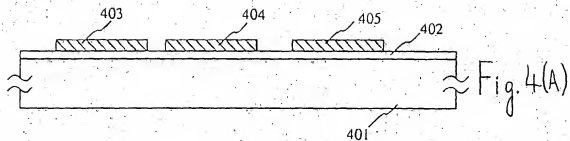


Fig. 3



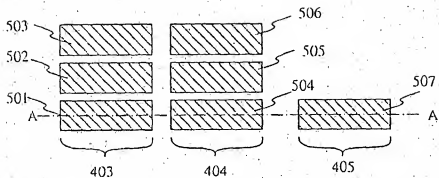


Fig. 5(A)

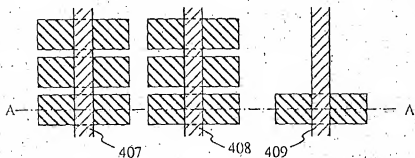


Fig. 5(B)

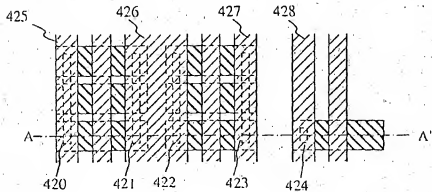


Fig. 5(C)

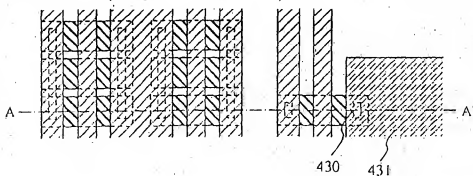


Fig. 5(D)